

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Mitsuhiro ICHIJO , <i>et al.</i>)	Group Art Unit: 2814
Application No. 10/804,053)	Examiner: Long Pham
Filed: March 19, 2004)	Confirmation No. 7738
For FILM FORMATION METHOD AND)	
MANUFACTURING METHOD OF		
SEMICONDUCTOR		

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401 Dulany Street
Alexandria, VA 22314

AMENDMENT

As part of a Request for Continued Examination (RCE), as submitted herewith, and further to the Advisory Action mailed **October 25, 2006**, and final Official Action mailed **June 28, 2006**, please amend the above-identified patent application, as follows: